

Scanning electron microscopy SEM

Scanning electron microscopy is a useful tool for observing small (microscopic/nanoscale) objects and generating high-resolution images at high magnifications. Different detectors provide different image qualities and are assessed based on which properties are to be optimized (In-lens, SE, BSE, CL).

In geological preparations, it is also often important to know something about the chemical composition and its distribution. For this reason, the microscopes are equipped with a number of detectors that can provide answers to precisely this (EDS, EBSD, WDS).

The institute has access to a wide range of analysis techniques, but currently only offers a limited selection. Get in touch for guidance.

<i>Microscope</i>	<i>Detector</i>	<i>Location</i>
Zeiss Sigma	Inlens, SE, BSE	KAM
Zeiss Merlin VP Compact	Inlens, SE, EDS, EBSD, WDS, CL, VP,	KAM
Hitachi TM 3030 Benchtop	BSE, EDS	IG

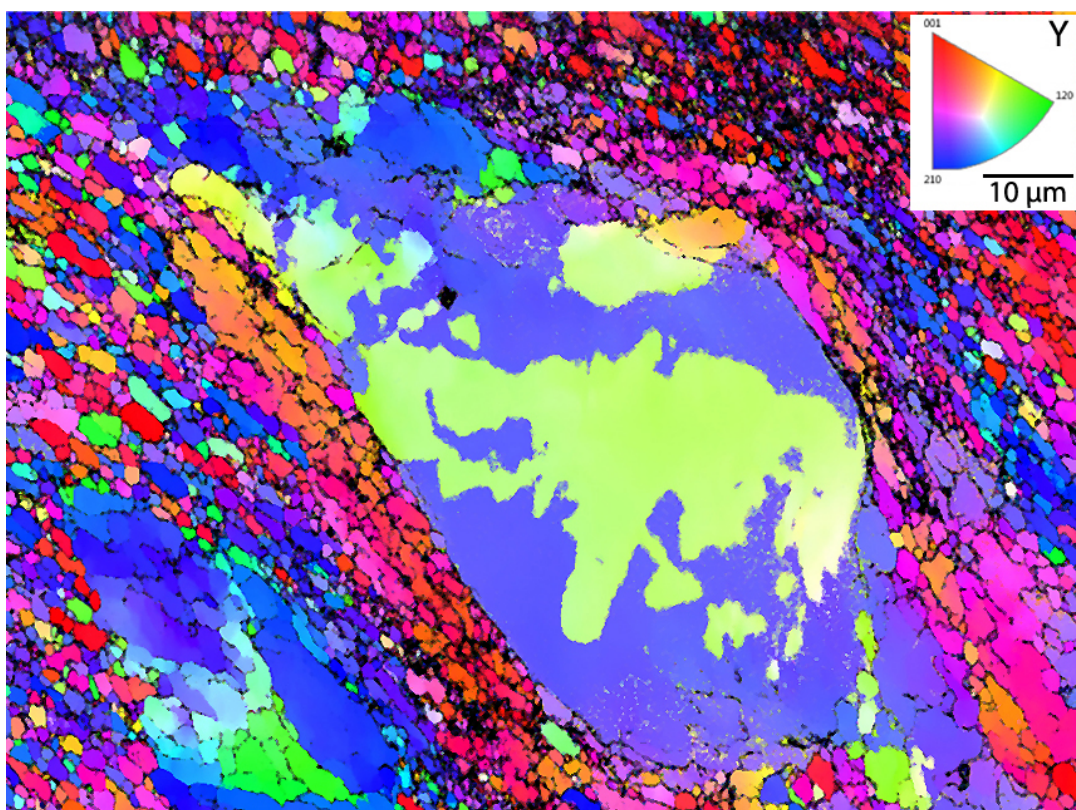
Link: [Instruments](#) | [UiT](#)



Photo: Kai Mortensen



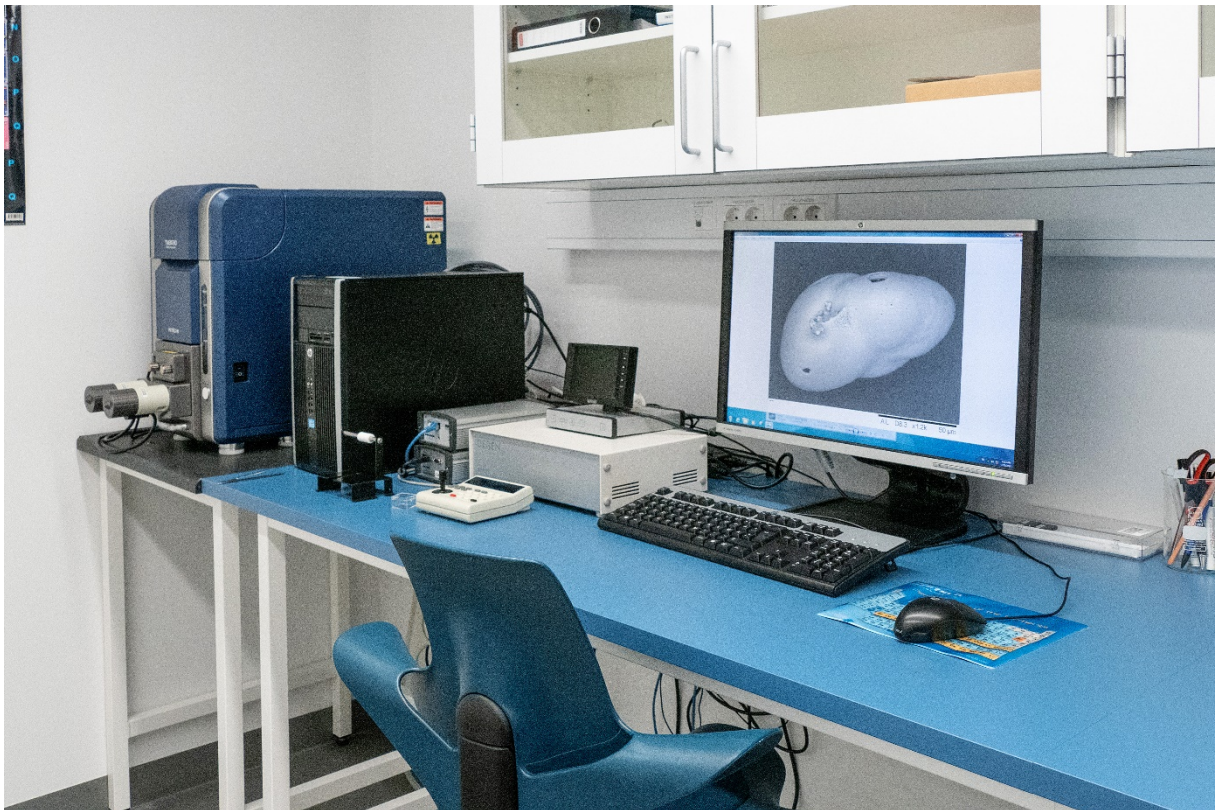
Photo: Kai Mortensen



EBSD map



Coater (photo: Kai Mortensen)



*Hitachi tabletop model is equipped with "tilt & rotation stage" as well as EDS detector.
Photo: Kai Mortensen*